MEMS Technology in Biomedical Sensor Application



Speaker: Susanna Chang Supervisor: Dr. Chii-Wann Lin 10/04/2002

Medical Micro Sensor and System Laboratory, Institute of Biomedical Engineering, National Taiwan University

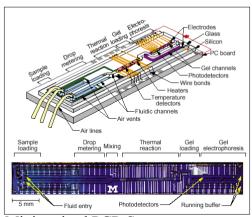
MEMS Technology in Biomedical Sensor Application

- **Presentation Outline**
- *Biomicroelectromechanical system (BioMEMS)
 *Microfabricated Biosensor Devices
 *State-of-the-art optical biosensor: SPR sensor
 *Frontier of Nanoscale biomolecular study
 *Conclusion

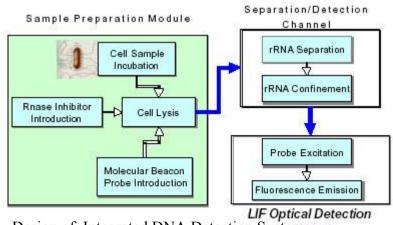


- Definition of <u>Bio-MicroelectroMechanical Systems</u> (BioMEMS):
- 1. From systemic aspect-

BioMEMS usually contains sensors, actuators, mechanical structures and electronics. Such systems are being developed as diagnostic and analytical devices at diagnostic and analytical devices. Suzanne Berry, TRENDS in Biotechnology Vol.20 No.1, pp.3, January 2002



Miniaturized PCR System Science,1998,282:484-487

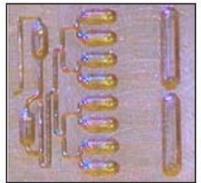


Design of Integrated DNA Detection System11 // http://ho.seas.ucla.eda

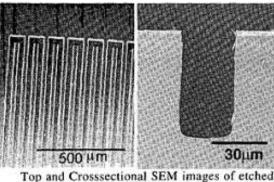
2. From component aspect

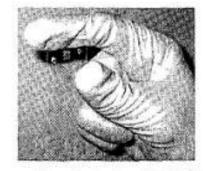
BioMEMS is the research of microfabricated devices for biological applications.

Tejal A. Desai et al, Biomolecular Engineering, 17 (2000) 23-36



PFCTM micro fluid analysis circuit in SeqPrepTM Chip



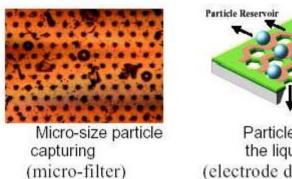


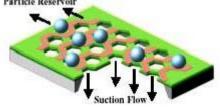
Top and Crosssectional SEM images of etche micro-capillary patterns.

Micro-capillary electrophoresis (µ-CE) chi

Kikuchi, T.; Ujiie, T.; Ichiki, T.; Horiike, Y. Microprocesses and Nanotechnology Conference, 1999.Digest of Papers. Microprocesses and Nanotechnology '99. 1999 International , pp178 –179,1999

3. MEMS technology is an engineering solution for biomedical problems





Particle transport into the liquid delivery system (electrode deposited micro-filter)

Airborne particle collection filter

http://ho.seas.ucla.eda

BioMEMS in **Biomedical** Field

BioMEMS encompasses all interfaces and intersections of the life sciences and clinical disciplines with microsystems and nanotechnology.

Related area:

- Micro & nanotechnology for drug delivery,
- Tissue engineering, harvesting, manipulation
- Biomolecular amplification,
- Sequencing of nucleic acids
- Proteomics
- Microfluidics and miniaturized total analysis systems (microTAS)
- Biosensors
- Molecular assembly,
- Nano-scale imaging, and integrated systems

Adapted from Cambridge Healthtech Institute http://www.genomicglossaries.com

Bio-microelectromechanical systems (bioMEMS)

MEMS

- Silicon based Material
- Electrical & Mechanical interface integration
- Moving part in micromachining system
 -active component

BioMEMS

- Biocompatible Material
- Biomolecular & physical parameter (electrical,mechanical optical) transducer integration
- Motion medium in passive substrate
- -microfluidic driving force

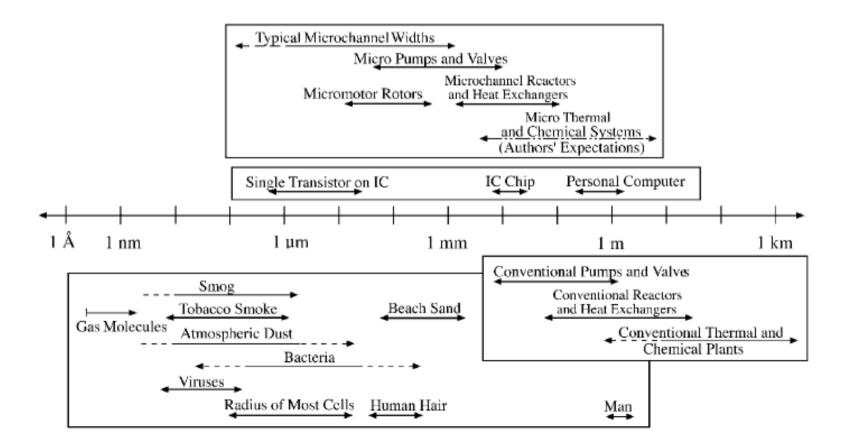
A quite different thinking process from MEMS to BioMEMS

Bio-microelectromechanical systems (bioMEMS)

A BioMEMS Platform for Biomedical Device?

- IC incompatible fabrication process (glass, polymer substrate)
- Batch manufacture is not a portion for each bio-based device.
- Biomaterial sterilization consideration
- BioMEMs packaging techniques for hybrid substrate or multichip system lead the way

BioMEMS in Biosensor Development A supporting technology for manipulating biomolecules at the micro-scale world.



Biosensor

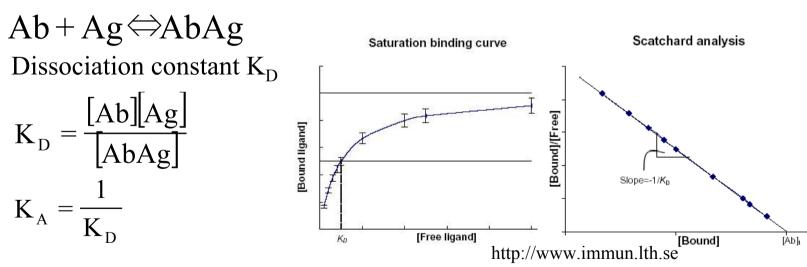
- Classfication
- 1.Electrochemical sensor
- 2.Immunosensor
 - Definition:

a sensor based on the pairing of a molecular recognition affinity pair. For i. e. Antigen(Ag)-Antibody(Ab) binding *electrochemical type-by chemicalelectical signal transform *optical type-by optoelectrical signal transform

Biosensor The affinity is a crucial concern

• Affinity is used to describe a reversible biomolecular interaction

also means the tightness of Ad-Ag binding



- Affinity determines the specificity of biosensor
- The nonspecific binding is an important issue when selecting Ag-Ab pairs

Optical Biosensor

Synonymous with optical immunosensor

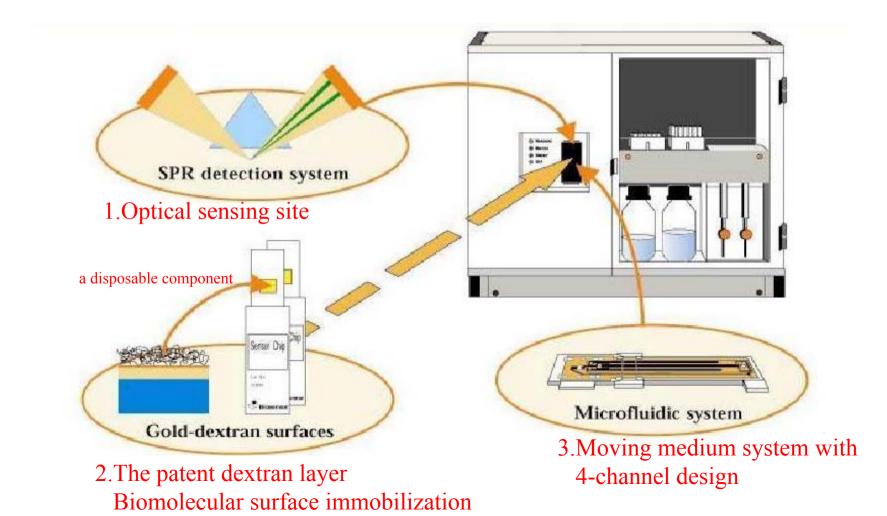
- 1.Simutaneous response time
- 2.No reference electrode requirement
- 3.Not subject to electrical interface and high sensitivity
- 3.Nondestructive method

4.Multiwavelength measurement at the same reagent

State-of-the-art optical biosensor: Surface Plasmon Resonance (SPR) Biosensor

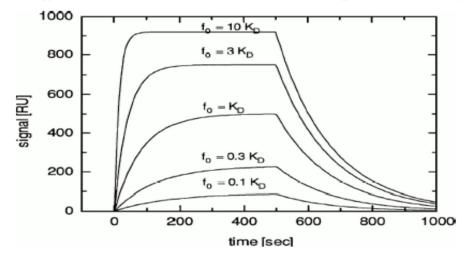


Surface Plasmon Resonance (SPR) Biosensor -the commercial scheme of BIAcore 2000 system



Surface Plasmon Resonance (SPR) Biosensor -Data analysis of BIAcore 2000 system

SPR typical association and dissociation curves with different ligand concentrations (f₀)



 $K_D = k_{off}/k_{on}$

association $k_{obs} = k_{on}f_0 + k_{off}$

 $R(t) = R_{eq}(f_0) [1 - exp(-k_{obs}t)]$

approaching equilibrium plateau signal

 $R_{eq} (f_0) = R_{max} [1 + k_{off}/(k_{en} + f_0)]^{-1} - R_{max} [1 + K_D/f_0]^{-1}$ does not require modeling of binding process, independent of mass transport limitations

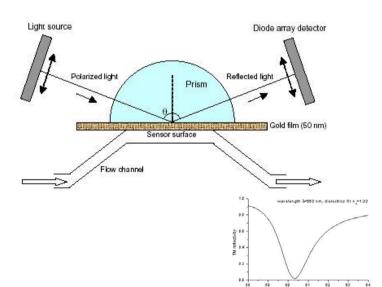
dissociation $(f_0 - 0, t > t_0)$

 $R(t) = R(t_0)exp[-k_{off}(t-t_0)]$

R is proportional to complex [XL], f₀ - [L]

The association and dissociation curve reveal the association/dissociation constant estimation SPR biosensor can be regarded as a vital research instrument for biomolecular kinetic mechanism research

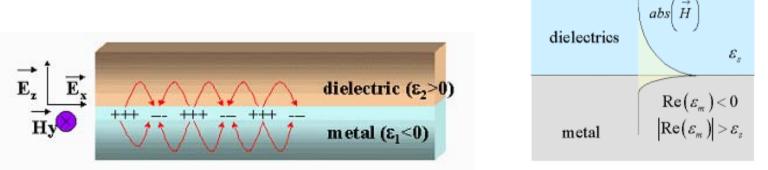
• An incident plane polarized light at a specific angle can be almost totally absorbed into a thin metal film(e.g., gold or silver) deposited onto a prism. The resonant coupling of the light energy into a free-electron cloud on the metal surface is called surface plasmon resonance



SPR sensing site components1.TM mode polarized light source2.High refractive index coupler3.Thin metal film(Au, Ag)4.Flow channel(optional)

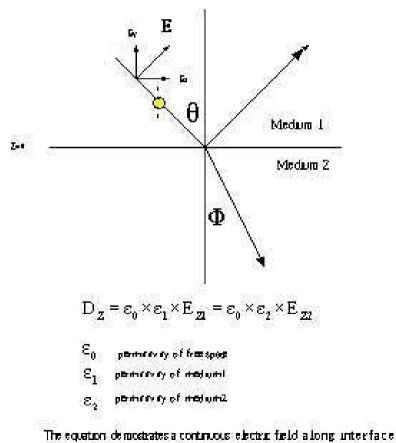
• What is SPR ???

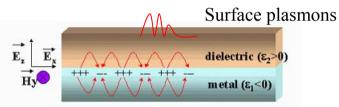
Definition: Surface plasmon resonance is a charge-density oscillation that exist at the interface of two media with dielectric constants of opposite signs.(e.g. metal & dielectric)



Surface plasma oscillations belongs to a transverse EM wave

• Optical excitation of SPR A p-polarized (TM mode) EM wave of incident light source





When surface plasmons are excited, there is a discontinuous electric field between interface due to free electron oscillation on metal layer

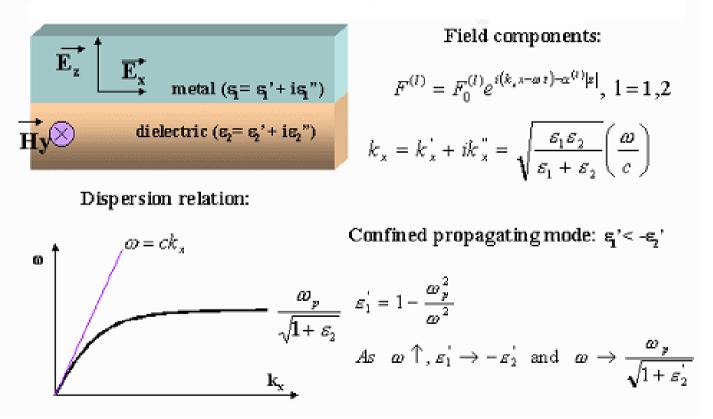
$$\varepsilon_{\rm metal} = 1 \neg (\omega_{\rm p} / \omega)^2$$

When $\omega < \omega_p$, electrons respond to the applied field and the dielectric constant of metal is negative.

- Maxwell equation of surface plasmon wave $E_{1} = (E_{x1}, 0, E_{Z1}) \times \exp[i(K_{x}.x_{\omega}t)]\exp(iK_{Z1}.Z)$ $E_{2} = (E_{x2}, 0, E_{Z2}) \times \exp[i(K_{x}.x_{\omega}t)]\exp(iK_{Z2}.Z)$ $H_{1} = (0, H_{Y1}, 0) \times \exp[i(K_{x}.x_{\omega}t)]\exp(iK_{Z1}.Z)$ $H_{2} = (0, H_{Y2}, 0) \times \exp[i(K_{x}.x_{\omega}t)]\exp(iK_{Z2}.Z)$
- Boundary condition: $E_{x1}=E_{x2}$ and $H_{y1}=H_{y2}$

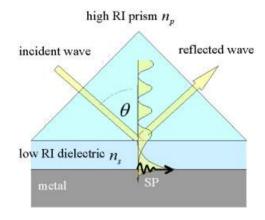
$$\frac{\varepsilon_1}{K_{Z1}} = \frac{\varepsilon_2}{K_{Z2}} \qquad K_{Z1} = \left(\neg K_x^2 + \varepsilon_1 \cdot K^2\right) \qquad K_{Z2} = \left(\neg K_x^2 + \varepsilon_2 \cdot K^2\right) \\ K_x = K\left(\left(\varepsilon_1 \cdot \varepsilon_2\right)/(\varepsilon_1 + \varepsilon_2)\right)^{1/2}$$

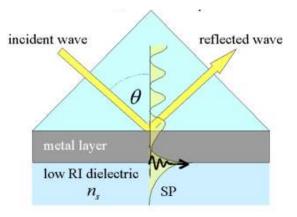
•Dispersion relation of surface plasmons

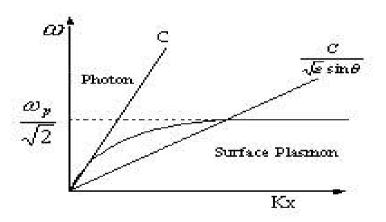


Surface plasmon can't be directly excited by an incident light

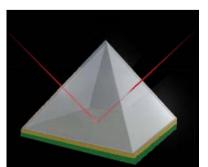
• The Otto/Kretschmann Configuration An evanescent field platform





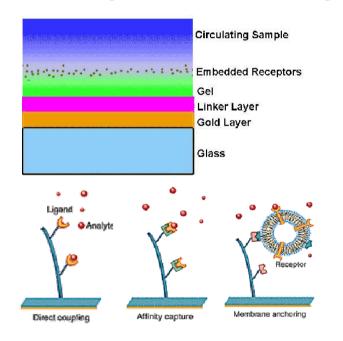


Dispersion relation of incident photon

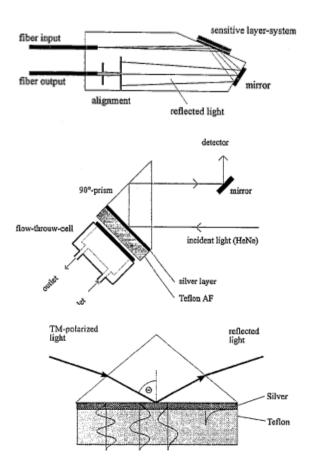


The Kretschmann /Otto Configuration the Evanescent Wave

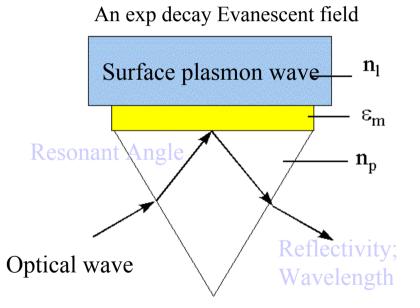
• Sensing element design

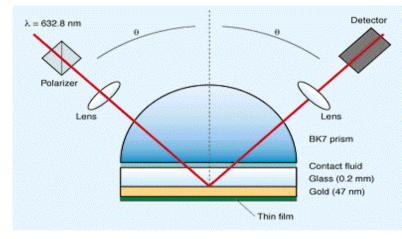


High affinity linker layer selsction

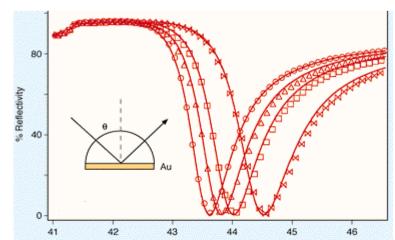


Optical System Layout for SPR Excitation





The Kretschmann configuration



SPR Angle Shift Measurement Fresnel Calculation

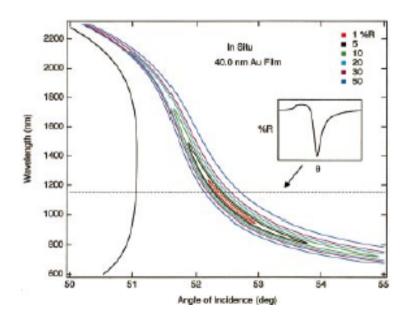
- Parameters-wavelength, reflectivity
- Complex 3-phase Fresnel calculation

prism/gold film/water

• A theoretical 2-dimension contour

// y-axis SPR reflectivitywavelength

// x-axis SPR reflectivityangle



Optical System Layout for SPR Excitation

• Fixed Angle Measureme Flow Cell Pinhole L2 Polarizer - SPR imaging system Gold Film Prism **Rotation Stage** a in situ measurement Collimator Detector 100 $\Delta \% R_{max} = 1.0\%$ Ж% 40 SPR imaging surface reconstruction 20 $\Delta n_{f} = 0.004$

50

52

54

θ (degrees)

56

⊳

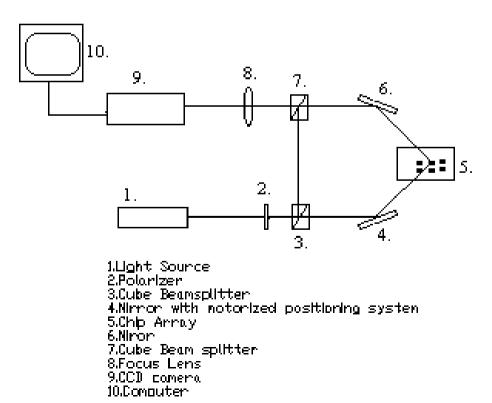
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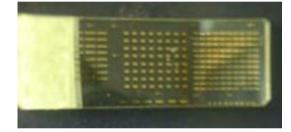
1-2

5.9

Optical System Layout for SPR Excitation

• Phase change Measurement





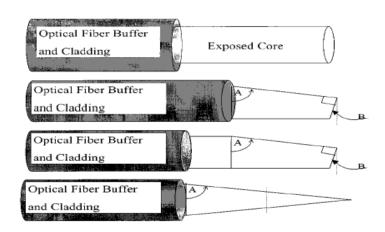
Wafer/Chip Cleaning	
Sp in Coating	
Lithograp hy	
Thermal Evaporation and Post-Deposition Annealing	 glass substrate Photoresist(PR) Layer PR after UV exposure
Lift-OffImmersion	🗖 Gold Layer

Miniaturation of SPR Optical System the optical fiber format

- Optic Fiber Consideration Fiber material-glass fiber , HiBi fiber Single mode or Multimode-
- Sensor Geometry Design
- Residual cladding depth(d_0)-
- Polish Side-
- Tip angle-resonant angle?
- Metal film thickness

45-75nm

• Homola(1996): Amplitude SPR sensor based on side polished single mode fiber offer superior sensitivity



Conclusion:

- Miniaturization optical device
- Enhance specificity
- Disposable component for point of care
- A near field imaging for nano-scale object

Thanks for your attention

